

Application Report Flow Sensors



Exhaust Monitoring of a MOCVD deposition systems

Description of the application:

MOCVD-deposition systems serve for the fabrication of Semiconductor components for LED's, high power transistor and lasers. The modular designed AIXTRON-machines are separated into four sections: Mixing and feeding of the process-gases, electronic control and the planetary reactor. An exhaust system is installed on each section and a SCHMIDT® Flow switch SS 20.200 cares for the reliable monitoring and with an alarm in case the flow velocity cannot guarantee a secure evacuation of harmful gases. The installation of the flow switches to the exhaust connection with a tube through passage is simple and quickly done as the patented sensors tip does not require precise aligned mounting. The SCHMIDT® Flow switches SS 20.200 have proofed their reliableness in practise.



Function of the Sensors:

Monitoring of the process-exhaust to avoid contamination of the service room with harmful gases.

Location of the Sensors:

In the exhaust-tubes of the system.

Branch:

Semiconductor plant construction

Sensor type used:

SCHMIDT® Flow Sensor SS 20.200

0..10 m/s 160 mm

Semiconductor relay (make contact) max 48V / 100mA / 300mW

Benefits and force of the SCHMIDT-Sensors:

- Simple and fast installation
- Omni directional measurement
- Compact design
- Reliable function
- Favourable price

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